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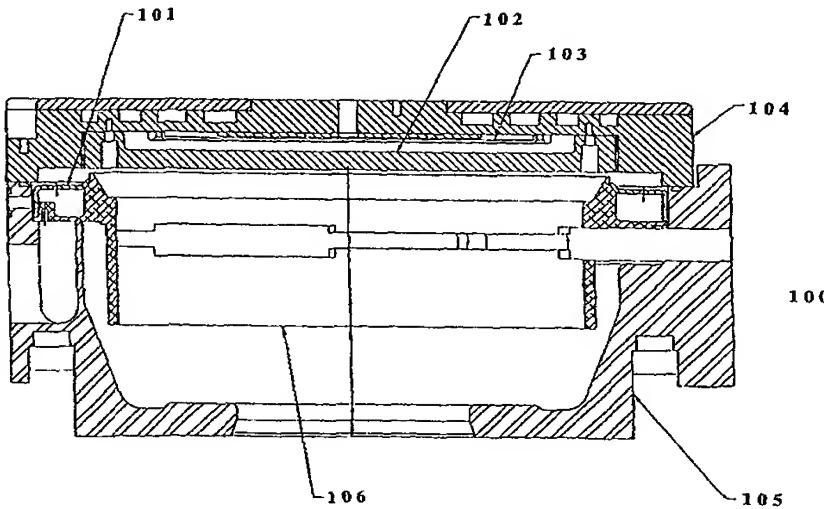
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(54) Title: EMISSIVITY-CHANGE-FREE PUMPING PLATE KIT IN A SINGLE WAFER CHAMBER



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(57) Abstract: Provided herein is an emissivity-change-free pumping plate kit used in a single wafer chamber (105). This kit comprises a top open pumping plate (106), and optionally a skirt and/or a second stage choking plate (101). The skirt may be installed around wafer heater, underneath wafer heater, or along chamber body inside the chamber. The choking plate is installed downstream of the top open pumping plate along the purge gas flow. Also provided is a method of preventing emissivity change and further providing optimal film thickness uniformity during wafer processing by utilizing such kit in the chamber.

INTERNATIONAL SEARCH REPORT

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A. CLASSIFICATION OF SUBJECT MATTER
IPC 7 C23C16/44 H01L21/00

According to International Patent Classification (IPC) or to both national classification and IPC

B. FIELDS SEARCHED

Minimum documentation searched (classification system followed by classification symbols)
IPC 7 C23C

Documentation searched other than minimum documentation to the extent that such documents are included in the fields searched

Electronic data base consulted during the international search (name of data base and, where practical, search terms used)

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C. DOCUMENTS CONSIDERED TO BE RELEVANT

Category ^a	Citation of document, with indication, where appropriate, of the relevant passages	Relevant to claim No.
X	EP 0 909 836 A (EBARA CORP) 21 April 1999 (1999-04-21) column 6, line 3 -column 8, line 37; figures 1A,1B,2,3	1-14
X	US 5 895 530 A (BRYANT TODD C ET AL) 20 April 1999 (1999-04-20) column 3, line 64 -column 8, line 14; figures	1,4,5,9, 10,13

Further documents are listed in the continuation of box C.

Patent family members are listed in annex.

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Information on patent family members

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Patent document cited in search report	Publication date		Patent family member(s)	Publication date
EP 0909836	A	21-04-1999	JP 11043773 A EP 0909836 A2 JP 11158632 A US 6176929 B1	16-02-1999 21-04-1999 15-06-1999 23-01-2001
US 5895530	A	20-04-1999	NONE	